

IN THE SPECIFICATION

Please amend the paragraph starting on page 9, line 12 as follows:

The tools 30-80 are grouped into sets of like tools, as denoted by lettered suffixes. For example, the set of tools 30A-30C represent tools of a certain type, such as a photolithography stepper. A particular wafer or lot of wafers progresses through the tools 30-80 as it is being manufactured, with each tool 30-80 performing a specific function in the process flow. Exemplary processing tools 30-80, include metrology tools and processing tools, such as photolithography steppers, etch tools, deposition tools, polishing tools, rapid thermal processing tools, implantation tools, etc. Typically, the path a particular wafer or lot passes through the process flow varies. Certain tools 30-80 may be out-of-service for maintenance or otherwise occupied processing other lots. The process control server 90 routes the individual lots through the process flow depending on the steps that need to be performed and the availabilities of the tools 30-80. A particular lot of wafers may pass through the same tool 30-80 more than once in its production (e.g., a particular stepper may be used for more than one masking operation).